

REMARKS

Status of the Application

Claims 1-4 are all the claims that have been examined in the application. Claims 1-4 stand rejected under 35 U.S.C. § 103(a) as being unpatentable over U.S. Patent 5,456,796 to Gupta et al.

Claim Rejections - 35 U.S.C. § 103

Claims 1-4 stand rejected under 35 U.S.C. § 103(a) as being unpatentable over U.S. Patent 5,456,796 to Gupta et al.

Claim 1 recites, in part, “exciting the gas in the reaction chamber by a radiofrequency excitation electromagnetic wave passing through a leakproof wall of dielectric material in order to generate a plasma.” The Examiner alleges that Gupta discloses all of the elements of claim 1. Applicant respectfully disagrees.

Gupta discloses that an inert gas may be used to fill the reaction chamber during a plasma ramp. When the plasma is at full power, reactants are introduced into the reaction chamber to process a semiconductor wafer. See col. 3, lines 29-33. However, Gupta indicates that an RF signal being slowly brought to full power is used to initiate the reaction. In Gupta, RF signal is applied to electrodes within the reaction chamber, not by passing an RF wave through a leakproof wall of dielectric material, as is recited in claim 1. Therefore, Gupta cannot disclose all of the elements of claim 1, and claim 1 is patentable over the applied art.

Claims 2-4 are patentable at least by virtue of their dependency from claim 1.

Conclusion

In view of the above, reconsideration and allowance of this application are now believed to be in order, and such actions are hereby solicited. If any points remain in issue which the Examiner feels may be best resolved through a personal or telephone interview, the Examiner is kindly requested to contact the undersigned at the telephone number listed below.

The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account.

Respectfully submitted,

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